

References:

- [1] V. Astié *et al.*, “Direct Liquid Injection Chemical Vapor Deposition,” in *Chemical Vapor Deposition for Nanotechnology*, IntechOpen, 2018. doi: 10.5772/intechopen.80244.
- [2] J. E. Maslar *et al.*, “Characterization of bubbler performance for low-volatility liquid precursor delivery,” *Journal of Vacuum Science & Technology A: Vacuum, Surfaces, and Films*, vol. 37, no. 4, p. 041506, Jul. 2019, doi: 10.1116/1.5099264.
- [3] C. Vahlas *et al.*, “Liquid and Solid Precursor Delivery Systems in Gas Phase Processes,” *MATS*, vol. 8, no. 2, pp. 91–108, May 2015, doi: 10.2174/1874464808666150324230711.